



SHEET 1 OF 1

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		DOCKET NO. 239720US90CONT		SERIAL NO. 10/608,032	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Toshio TSUKAKOSHI			
				FILING DATE June 30, 2003		GROUP 2121	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
120	AA	6,248,486	06/19/2001	P. DIRKSEN, et al.			
120	AB	2002/0008869 A1	01/24/2002	H. VAN DER LAAN, et al.			
120	AC	2002/0036758 A1	03/28/2002	C. G. M. DE MOL, et al.			
120	AD	2002/0191165 A1	12/19/2002	J. J. M. BASELMANS, et al.			
120	AE	5,978,085	11/02/1999	A. H. SMITH, et al.			
	AF						
	AG						
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
120	AK	1 160 626	12/05/2001	EUROPE			
120	AL	WO 00/31592	06/02/2000	WIPO			
120	AM	1 128 217	08/29/2001	EUROPE			
120	AN	10-154657	06/09/1998	JAPAN (with English Abstract)			X
120	AO	2000-121491	04/28/2000	JAPAN (with English Abstract)			X
120	AP	WO 99/60361	11/25/1999	WIPO (with English Abstract)			X
120	AQ	1 079 223	02/28/2001	EUROPE			
120	AR	11-118613	04/30/1999	JAPAN			X
120	AS	6-235619	08/23/1994	JAPAN			X
120	AT	5-296879	11/12/1993	JAPAN			X
120	AU	2000-47103	02/18/2000	JAPAN			X
120	AV	2000-331923	11/30/2000	JAPAN			X
120	AW	11-233424	08/27/1999	JAPAN			X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
120	AX	D. G. FLAGELLO, et al., SPIE Microlithography Seminar, pages 1-14, " TOWARDS A COMPREHENSIVE CONTROL OF FULL-FIELD IMAGE QUALITY IN OPTICAL PHOTOLITHOGRAPHY ", March 1997					
	AY						
	AZ						<input type="checkbox"/> Additional References sheet(s) attached
Examiner <i>David J. [Signature]</i>					Date Considered 5-14-04		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							